H 5244 US
21.05.2001

WHAT IS CLAIMED IS:

Sub A6

1. A substrate conveying module (1) for conveying substrates into a workstation (3), the substrate conveying module (1) being surrounded by side walls (1a, b, c), wherein at least two side walls (1a, b, c) of the substrate conveying module (1) have mechanical connecting elements (4a) that coact with corresponding connecting elements (4b) of the workstation (3).

2. The substrate conveying module (1) as defined in Claim 1, wherein kinematic couplings are provided as the connecting elements (4a, b).

3. The substrate conveying module (1) as defined in Claim 1, wherein at least one side wall (1a, b, c) of the substrate conveying module (1) has one or more load ports (2a, b, c, d) for the loading and unloading of substrates into and from the substrate conveying module (1).

4. The substrate conveying module (1) as defined in Claim 1, wherein the workstation (3) is provided for the inspection, measurement, or processing of the substrates.

Sub A7

5. A system made up of at least one substrate conveying module (1) and at least one workstation (3) which has several side walls (3a, b, c, d), substrates being exchangeable between the substrate conveying module (1) and workstation (3), wherein the workstation (3) has, on at least two different side walls (3a, b, c, d), connecting elements (4b) that coact with the corresponding connecting elements (4a) in at least one side wall (1a, b, c) of the substrate conveying module (1).

6. The system as defined in Claim 5, wherein kinematic couplings are provided as the connecting elements (4a, b).

H 5244 US
21.05.2001

Subeı

7. The system as defined in Claim 5, wherein the substrate conveying module (1) has one or more load ports (2a, b, c, d) for the loading and unloading of substrates into and from the substrate conveying module (1).

8. The system as defined in Claim 5, wherein the workstation (3) is provided for the inspection, measurement, or processing of the substrates.

9. The system as defined in Claim 5, characterized by a permanently set transfer point (5) for the substrates in the context of exchange of the substrates between the substrate conveying module (1) and the workstation (3).

add B17